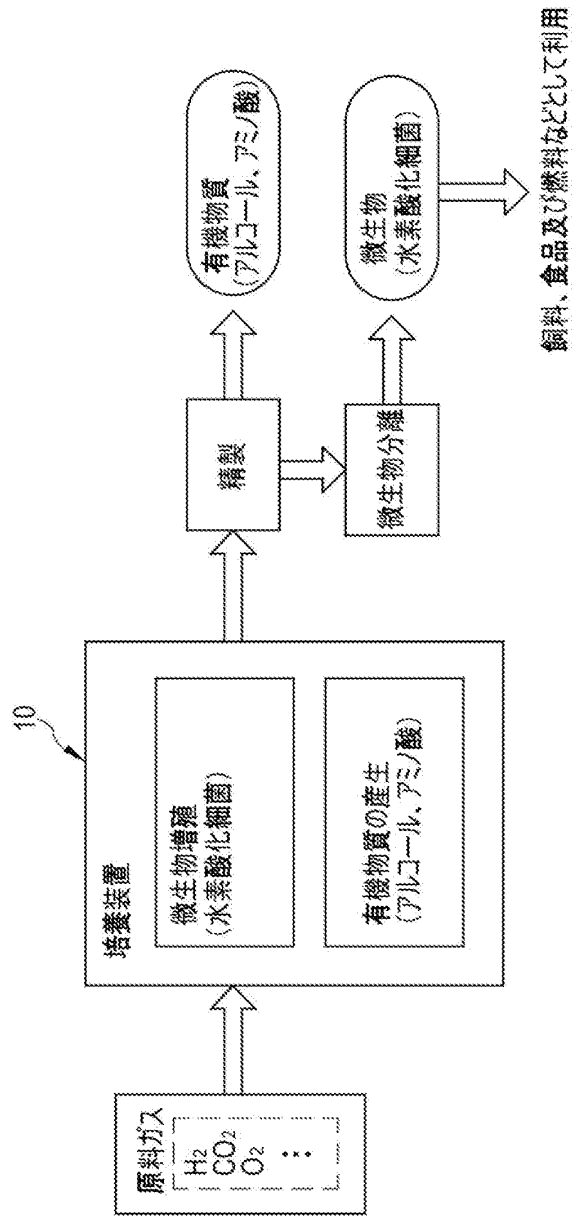
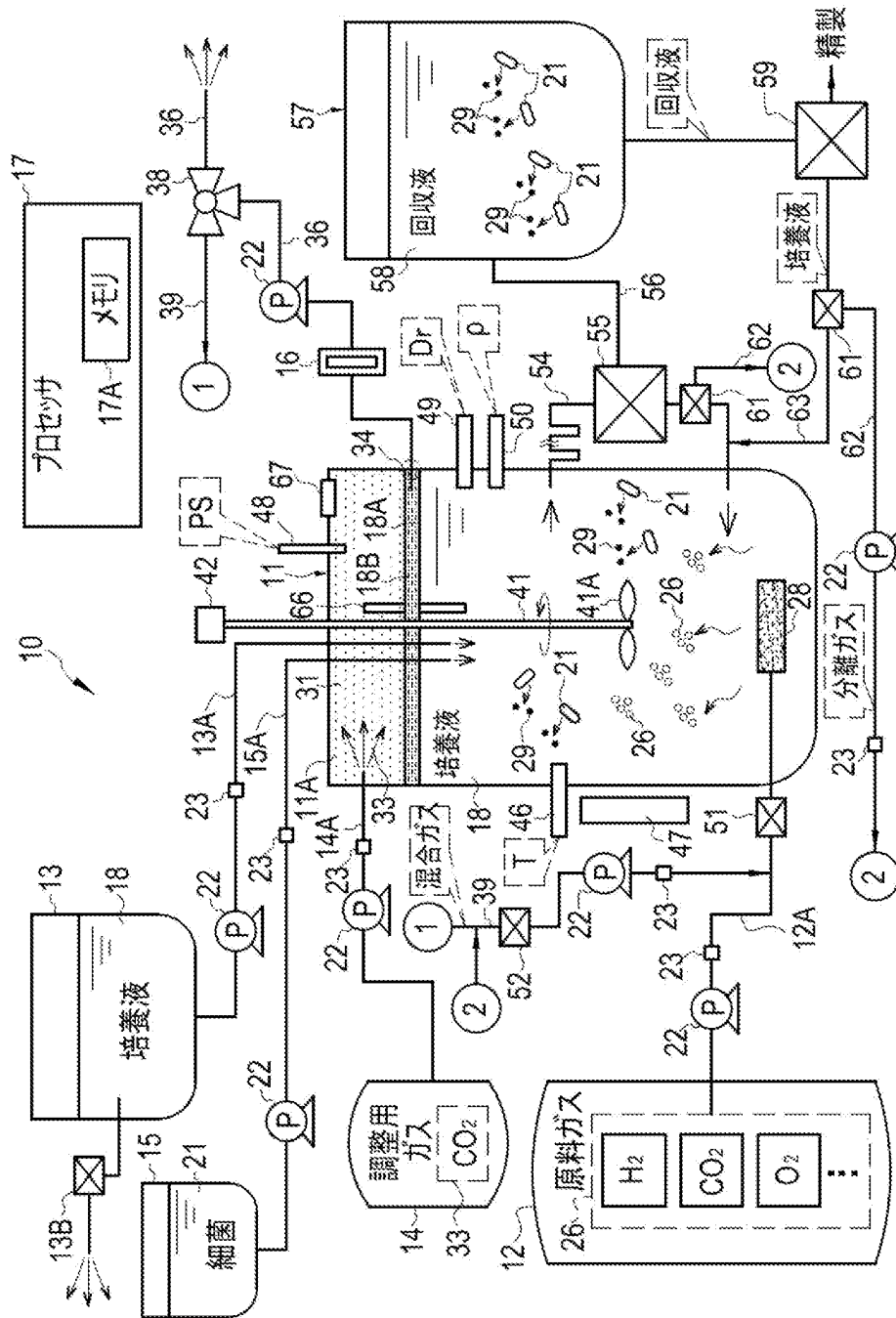
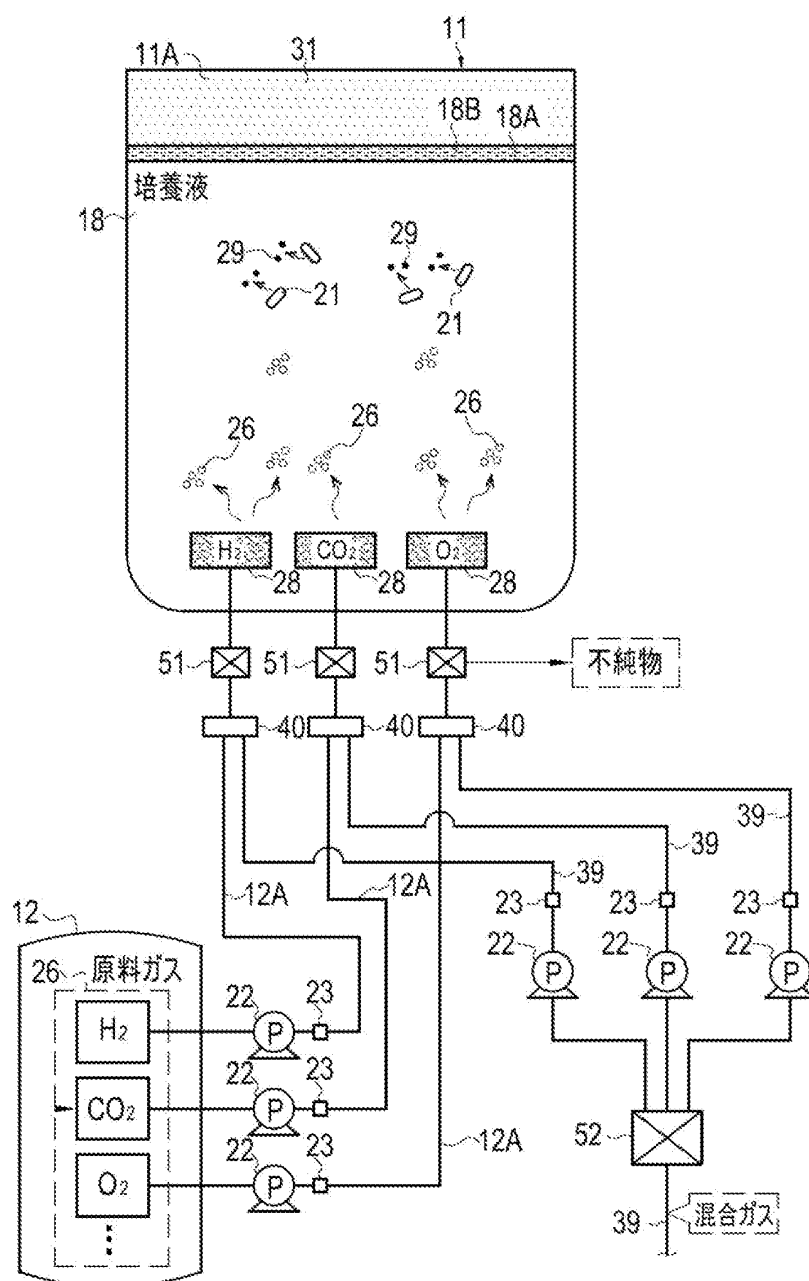


[図1]

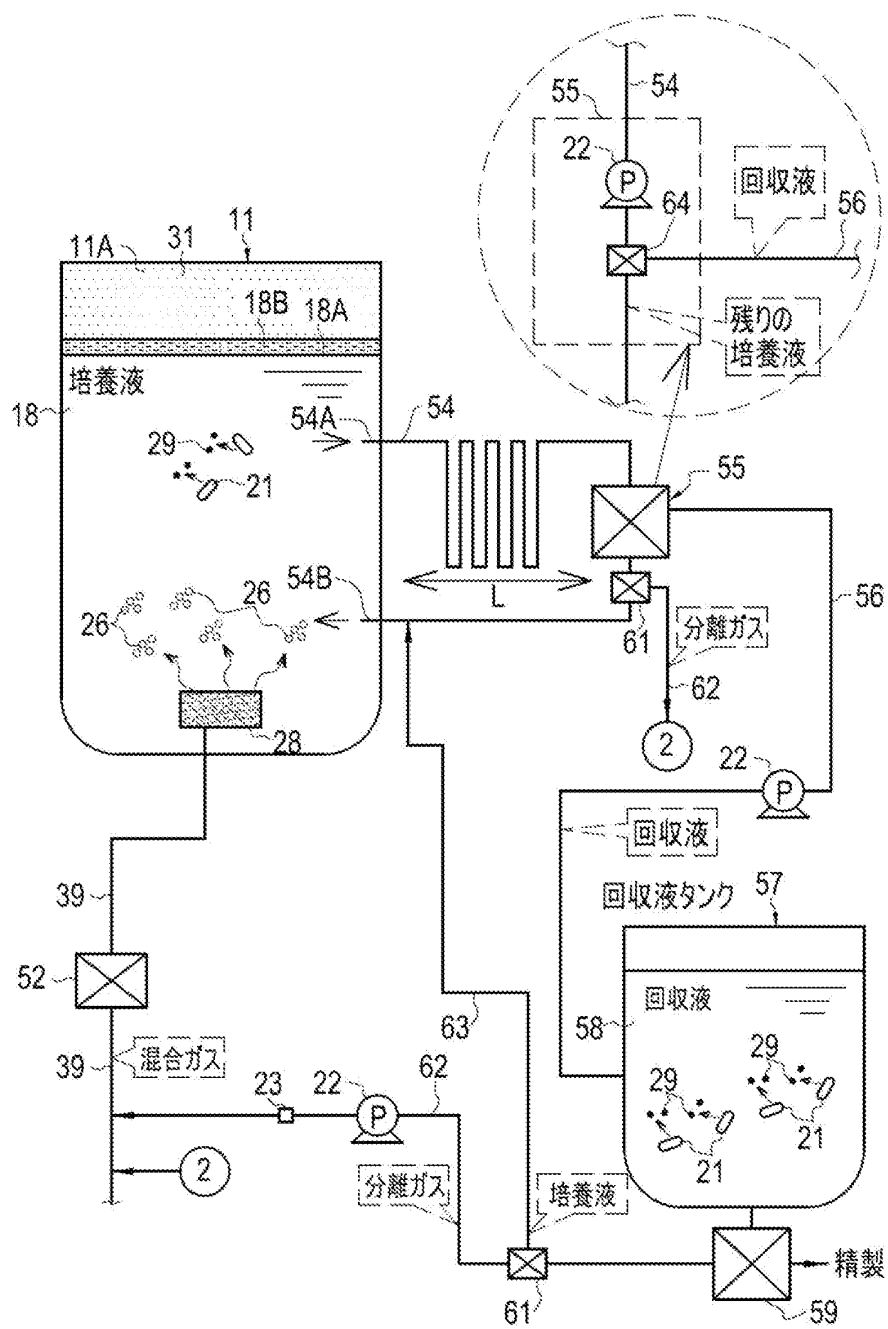


[図2]

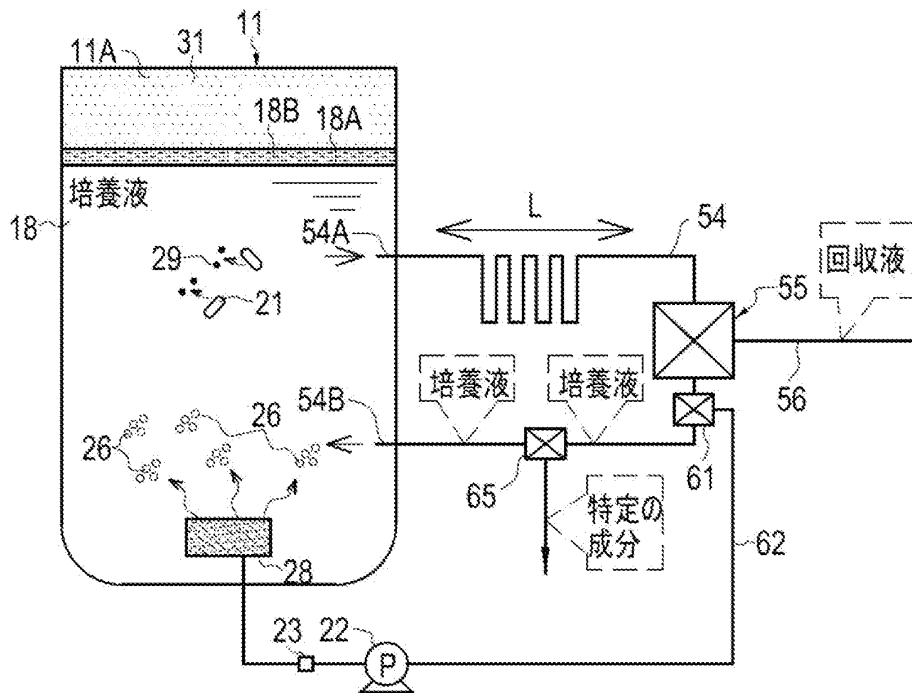




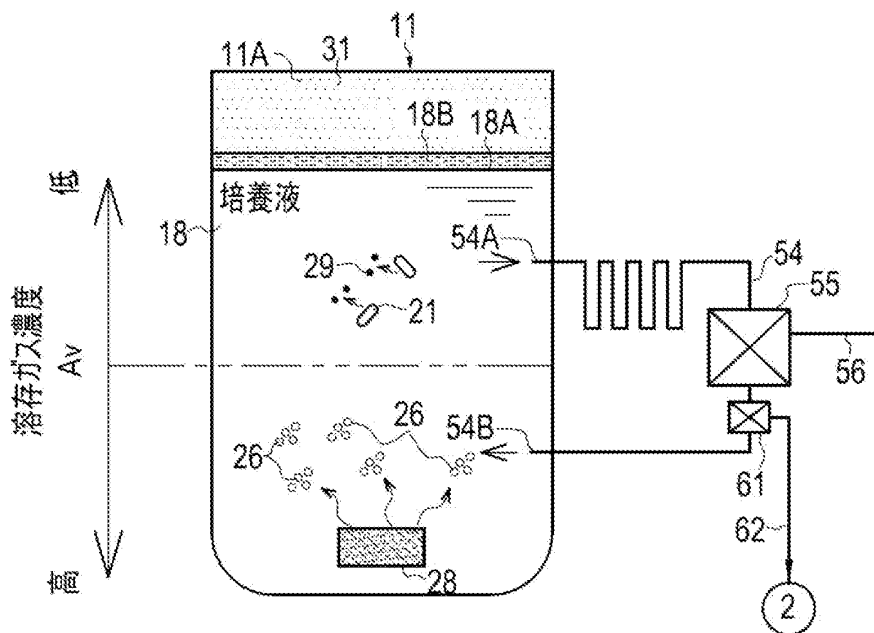
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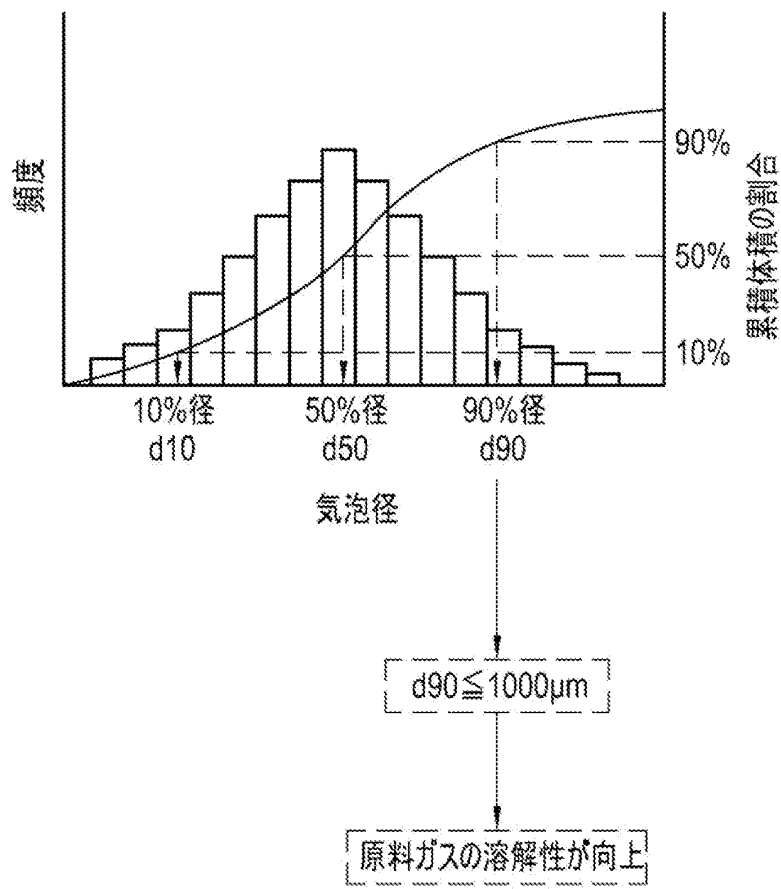
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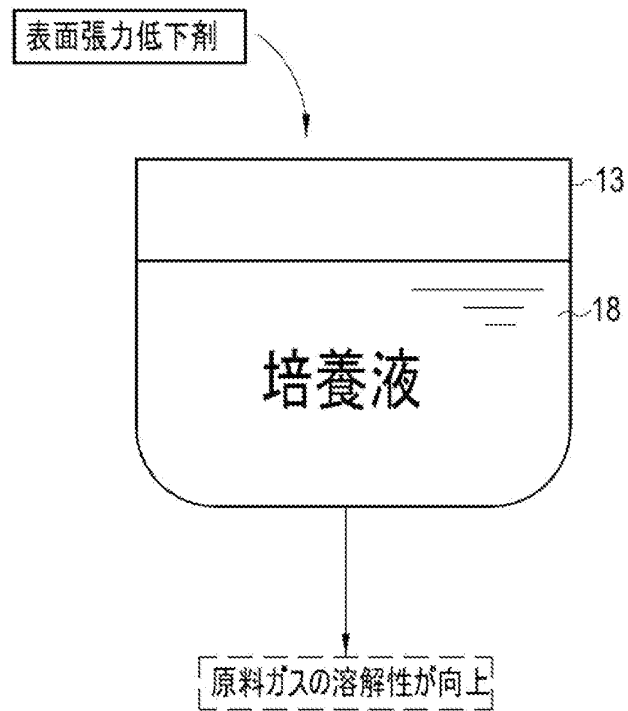
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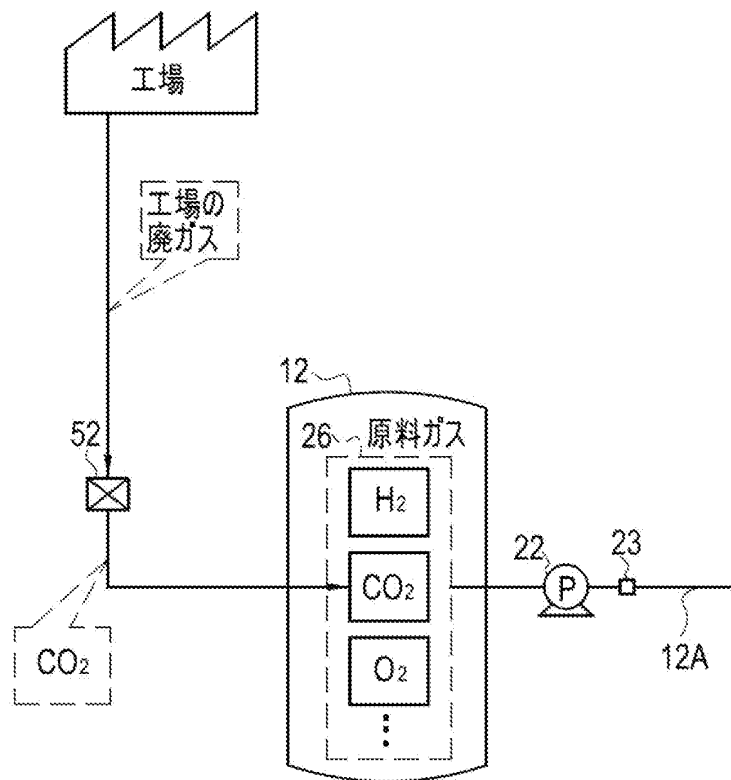
[図7]



[図8]



[図9]



[図10]

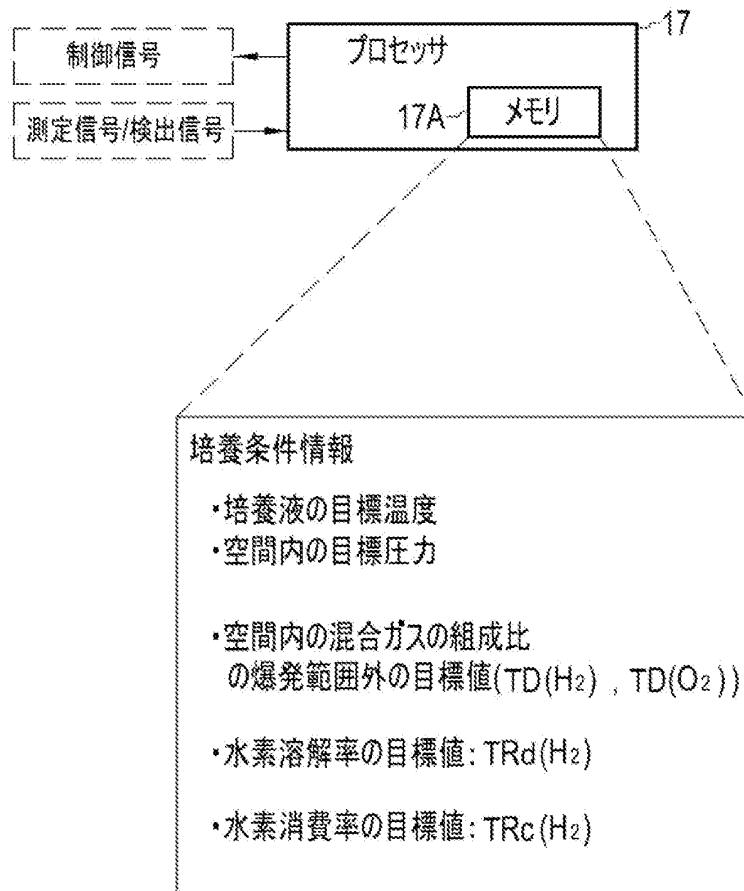
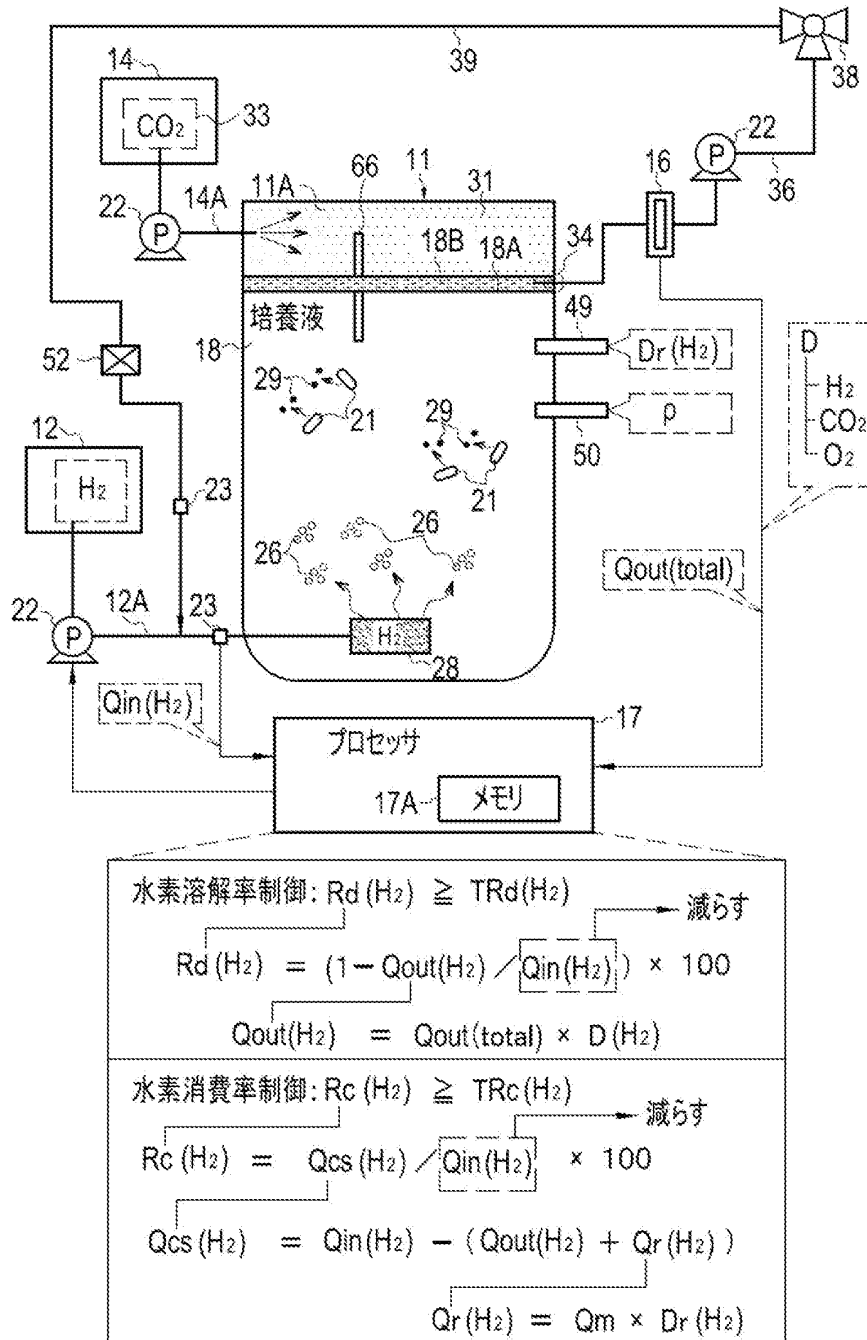
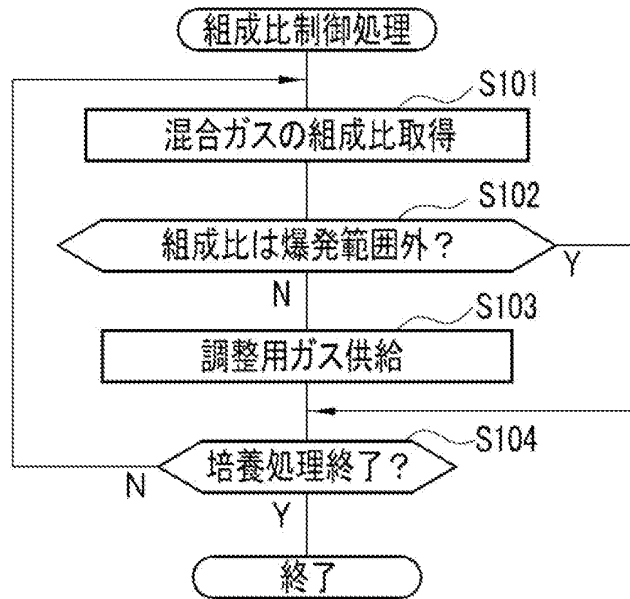


Figure 1 is a schematic diagram of a culture apparatus 10. The apparatus includes a CO₂ source 14 connected to a pump 22, which feeds CO₂ into a culture vessel 11 through a gas inlet 11A. The vessel contains a culture liquid 18, a stirrer 21, and a heater 28. A gas outlet 11B leads from the vessel to a gas separator 16, which is connected to a pump 22 and a gas outlet 36. A gas composition sensor 34 is located between the vessel and the separator. The sensor outputs data to a processor 17, which includes a memory 17A. The processor controls the CO₂ supply and the gas composition. A detailed view of the gas composition control shows the ratio of D(H₂), D(O₂), and D(CO₂) being adjusted to maintain a target ratio TD(H₂), TD(O₂).

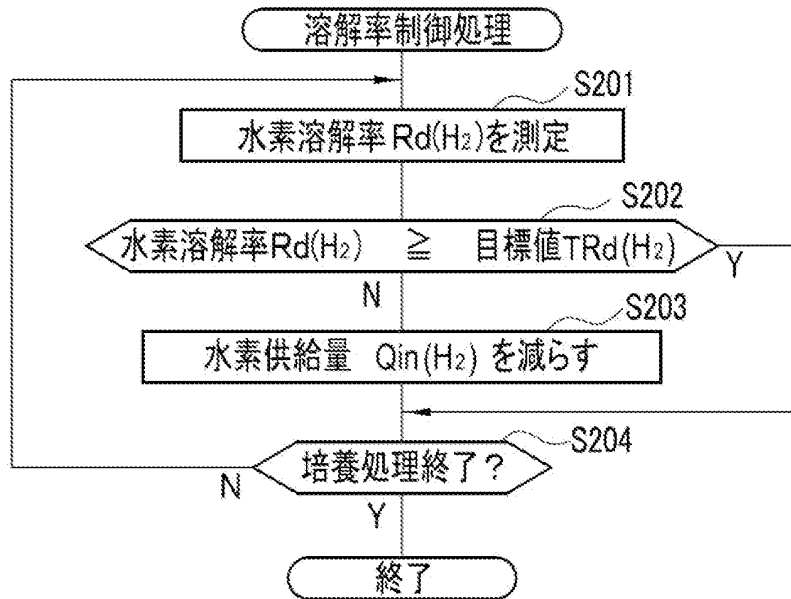
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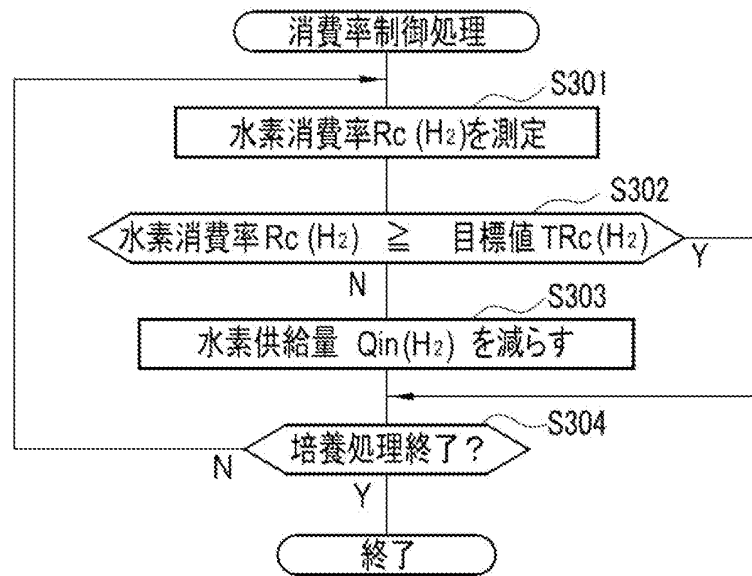
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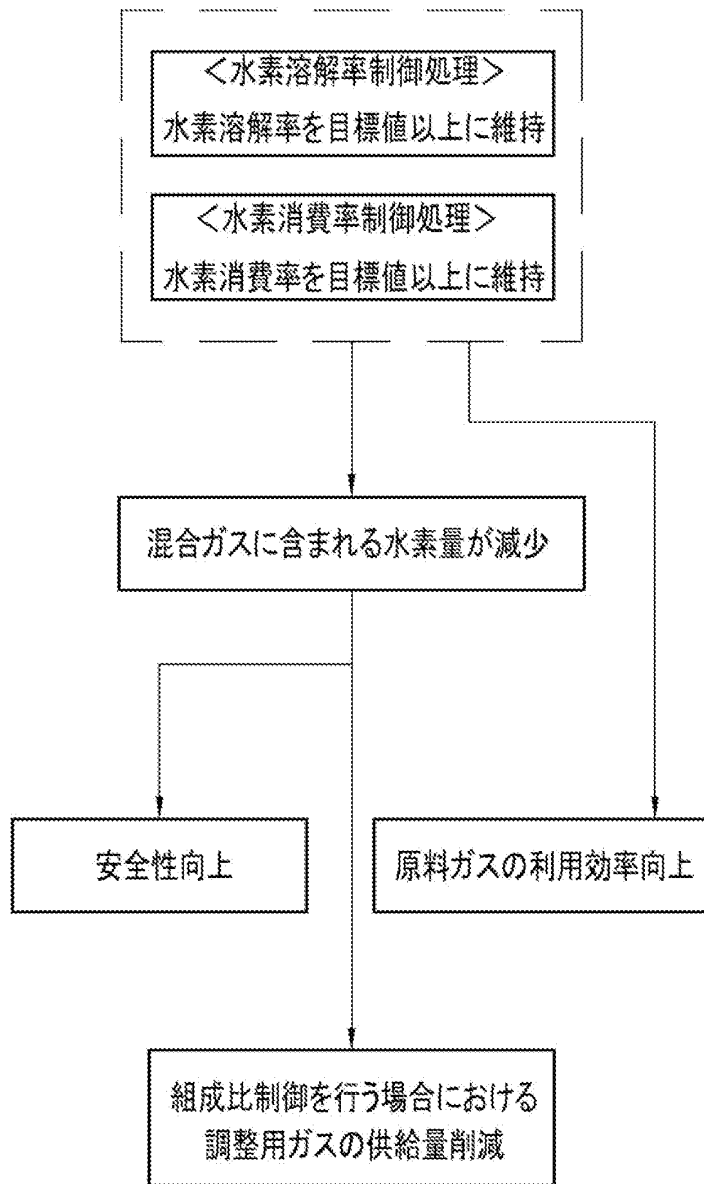
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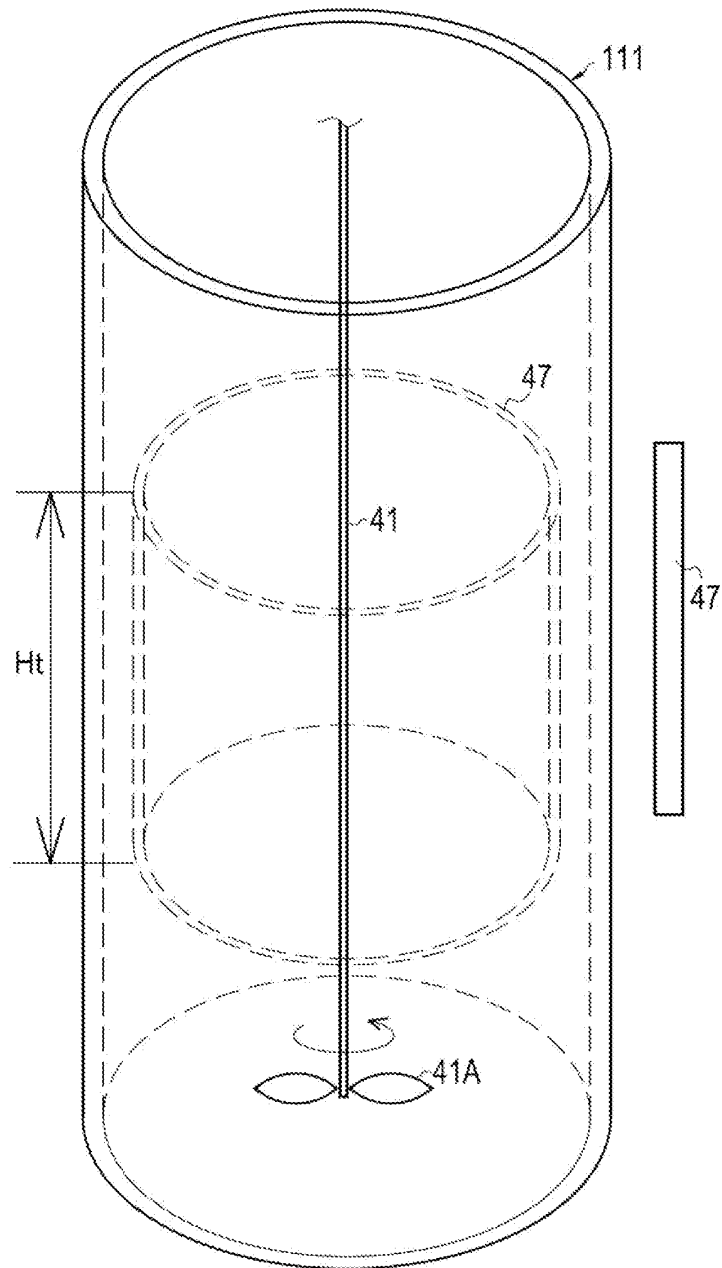
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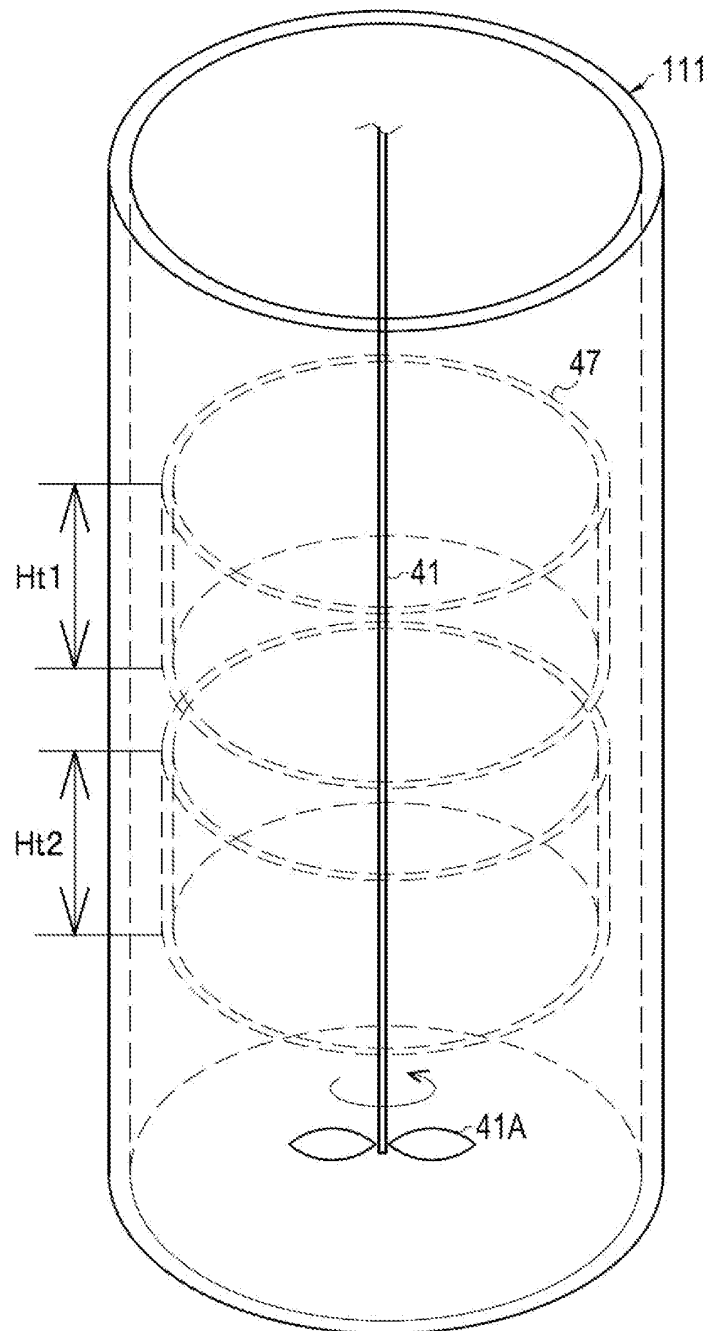
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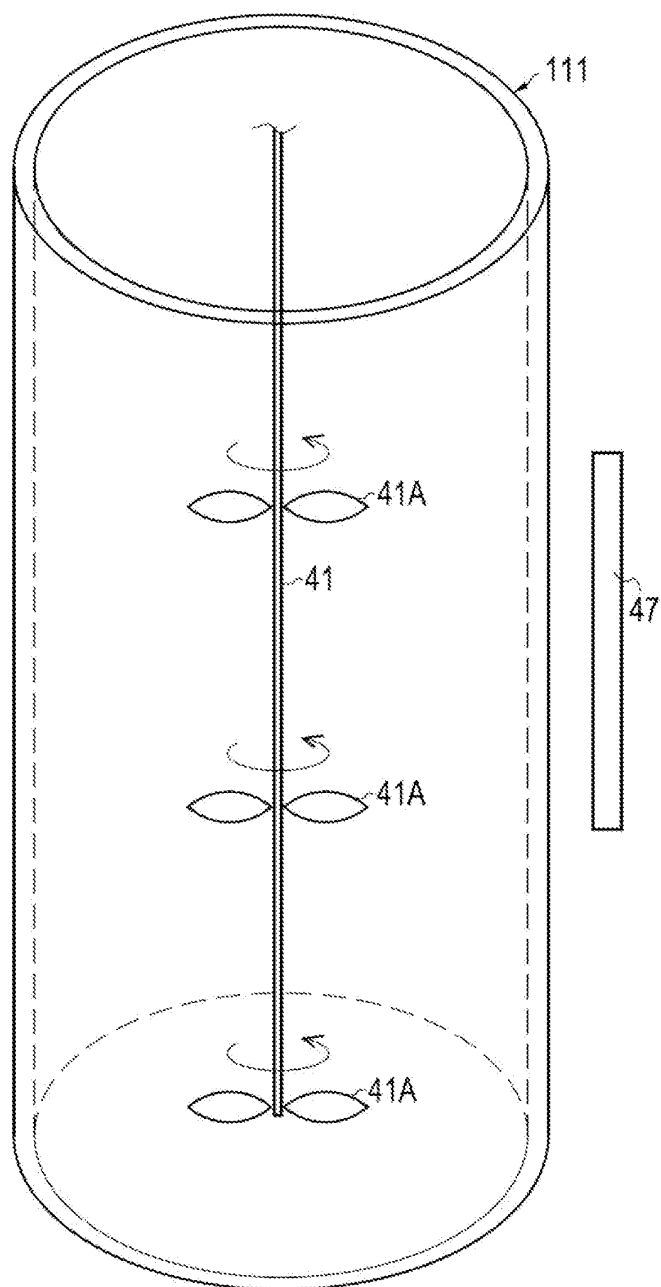
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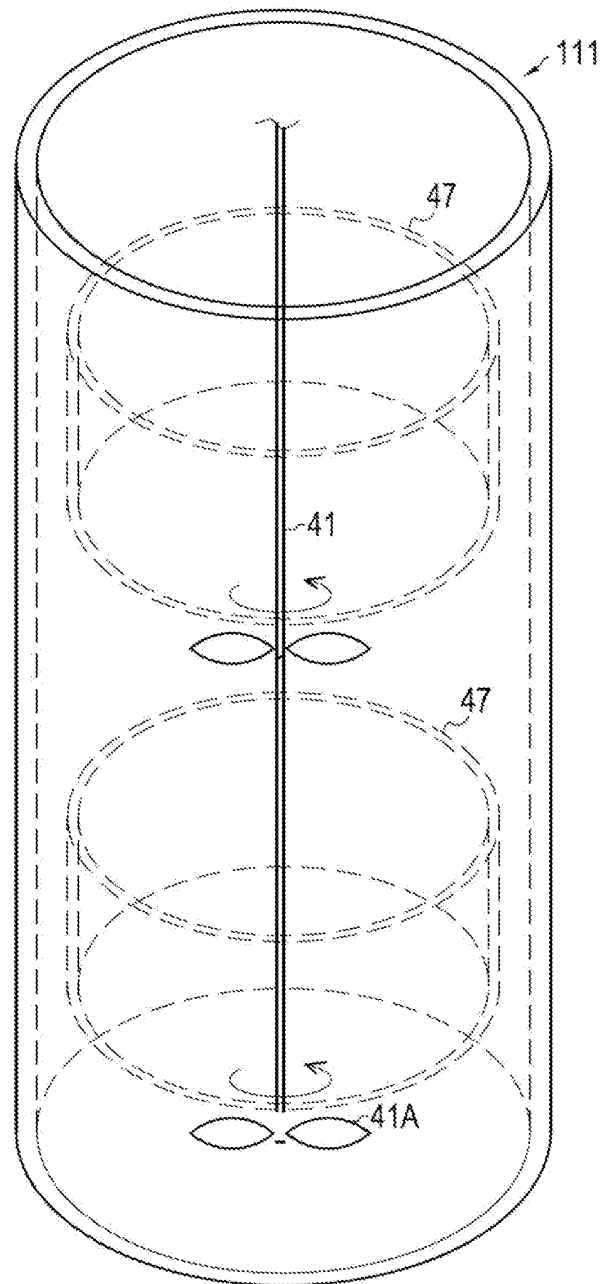
[図19]



[図20]



[図21]



[図22]

